

OXFORD PLASMA LAB-100 CLUSTER TOOL

- **Complete ICP/RIE Chamber (RH side) (380 ICP)**
Includes everything (Baratrons, Penning Gage, Turbo Pump, VAT Gate valve and APC with PM5 Controller, Slit VAT Valve, Mechanical Clamp Quartz 6", Top Ceramics tube, Lower Electrode)
- **Complete PECVD Chamber (LH Side) (100+PECVD)** Includes everything (Baratrons, APC VAT Gate valve with PM5 Controller, Slit VAT Valve, DSS Ring, Gas Shower, Lower Electrode)
- **COMPLETE LOADLOCK MODULE: (Middle)**
- 4 RF Generators :
Advances Energy (RFPP) -5 LF (50Khz-400Khz) FOR PECVD
Advanced Energy High Lite 136 For RIE
COMDELL RF-600X for PECVD
ADVANCED ENERGY- For ICP
- **PC Computer with PC2000 Oxford Software.**
- **ENDPOINT DETECTOR LASER (EPD) for ICP/RIE chamber (Sophie)**
- **2 Gas Pods** with 10 MFCs model MKS 1179A
ICP/RIE Gas Pod:
SF6- 50sccm
O2-50sccm
He-200sccm
C4F8-100sccm
- **PECVD Gas Pod**
NH3-100sccm
N2O- 3 SLM
Ar 90% +B2H6 10% - 50sccm (Boron)
Ar 90% +PH3 10%- 50sccm (Phosphine)
N2 95% + Sih4 5%- 1 SLM (Silane)
Ar 90% + GeH4 10% - 50 sccm (Germane)
- CHILLER for ICP/RIE Process Cooling Control.
- TRANSFORMER 3 Phase.
- Vacuum Pumps x 3